



**THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Patent Application of

VEERASAMY et al.

Atty. Ref.: 3691-356; Confirmation No. 8233

Appl. No. 10/003,436

TC/A.U. 1762

Filed: December 6, 2001

Examiner: Chen, B.

For: METHOD OF ION BEAM MILLING A GLASS SUBSTRATE PRIOR TO  
DEPOSITING A COATING SYSTEM THEREON, AND CORRESPONDING  
SYSTEM FOR CARRYING OUT THE SAME

\* \* \* \* \*

March 5, 2004

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

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**MAR 12 2004**

**AMENDMENT**

Responsive to the Official Action dated March 2, 2004, please amend the  
above-identified application as follows: